



AMENDMENT UNDER 37 C.F.R. § 1.116
EXPEDITING PROCEDURE
EXAMINING GROUP 1700

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Luetzen, *et al.* Docket No.: INF115
Serial No.: 10/721,225 Art Unit: 1763
Filed: November 26, 2003 Examiner: George A. Goudreau
For: Method and Structures for Increasing the Structure Density and the Storage
Capacitance in a Semiconductor Wafer

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 C.F.R. § 1.116

Dear Sir:

Applicants respectfully submit the following amendments and remarks in response to Examiner's Office Action dated October 31, 2006, which Action is made final. Applicants respectfully request that these amendments and remarks be entered in pursuant to the provisions of 37 CFR § 1.116, and respectfully request reconsideration of claims 1-13 and 21-27.